

## Supplemental Document

Figure 1a illustrates the schematics of the ALD-IGZO Top-gate TFT structure with gate insulator of  $\text{Al}_2\text{O}_3$  (A20),  $\text{SiO}_2$  (S20), and  $\text{SiO}_2/\text{Al}_2\text{O}_3$  (SA). Figure 1b shows the electrical properties of single and heterogeneous gate insulator TFTs. Figure 1c is the representative transfer curves for A20, S20, and SA-TFTs under PBTS conditions (electric field = 2 MV/cm and temperature = 60 °C for 1 h). Figure 1d is the constant current stability (CCS) of A20-, S20-, and SA-TFTs under  $V_{\text{GS}} = 4$  V and  $V_{\text{DS}} = 1$  V for 1 hour with the illustration of the reliability compensation concept based on the quantitative comparison between electron trapping sites in gate insulator and donor-induced species in A20-, S20-, and SA-TFTs.

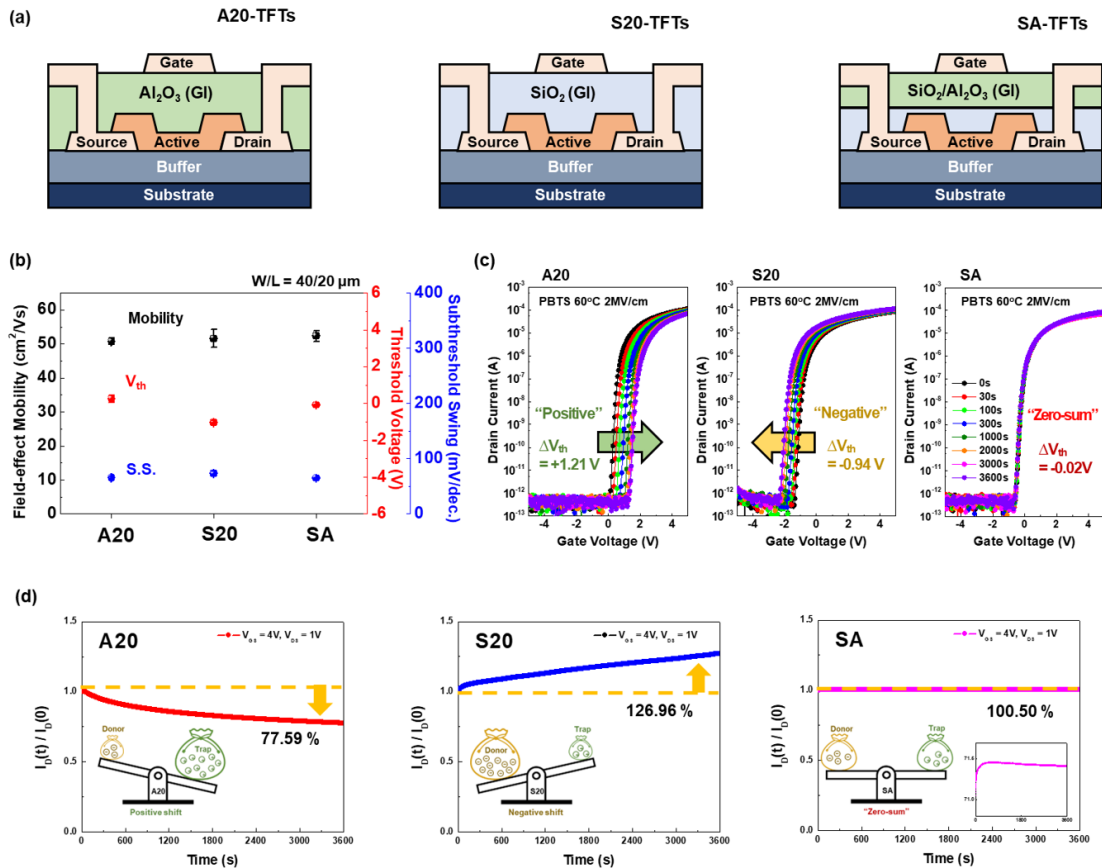


Figure 1. (a) Schematics of ALD-IGZO Top-gate TFT structure with gate insulator of  $\text{Al}_2\text{O}_3$  (A20),  $\text{SiO}_2$  (S20), and  $\text{SiO}_2/\text{Al}_2\text{O}_3$  (SA). (b) Summary of electrical properties of single and heterogeneous gate insulator TFTs (average value ( $\pm$  standard deviation) extracted from evaluated devices). (c) Representative transfer curves for A20, S20 and SA-TFTs under PBTS condition (electric field = 2 MV/cm and temperature = 60 °C for 1 h). (d) The constant current stability (CCS) of A20-, S20-, and SA-TFTs under  $V_{\text{GS}} = 4$  V and  $V_{\text{DS}} = 1$  V for 1 hour with the illustration of the reliability compensation concept based on the quantitative comparison between electron trapping sites in gate insulator and donor-induced species.